



PATENT  
Customer No. 22,852  
Attorney Docket No. 04329.3178

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of: )  
)  
Yukiteru MATSUI et al. ) Group Art Unit: 2812  
)  
Serial No.: 10/706,052 ) Examiner: Gurley, Lynne A.  
)  
Filed: November 13, 2003 )  
)  
For: SLURRY FOR CMP, AND )  
METHOD OF MANUFACTURING )  
SEMICONDUCTOR DEVICE )

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

**RESPONSE TO RESTRICTION REQUIREMENT**

In the Office Action dated March 25, 2004, the period for response to which extends through April 25, 2004, the Examiner required restriction under 35 U.S.C. § 121 between the following groups:

Group I, claims 8-20, characterized by the Examiner as drawn to a method of making a semiconductor device using a CMP slurry; and

Group II, claims 1-7, characterized by the Examiner as drawn to a CMP slurry.


Applicants provisionally elect to prosecute Group I, including claims 8-20, without traverse.

Please grant any extensions of time required to enter this response and charge any additional required fees to our deposit account 06-0916.

Respectfully submitted,

FINNEGAN, HENDERSON, FARABOW,  
GARRETT & DUNNER, L.L.P.

Dated: April 23, 2004

By:   
Qingyu Yin\*

\*With limited recognition under 37 C.F.R. § 10.9(b)